



PATENT  
97-CT-174

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: )  
RAFFAELE ZAMBRANO )  
Serial No.: 09/191,743 )  
Filed: November 13, 1998 )  
For: IN-SITU DEPOSITION AND DOPING )  
PROCESS FOR POLYCRYSTALLINE )  
SILICON LAYERS AND THE RESULTING )  
DEVICE )

Group Art Unit: 2815

Examiner: C. Whitehead

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PETITION FOR EXTENSION OF TIME TECHNOLOGY CENTER 2800

Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

In accordance with Rule 1.136, the applicant respectfully petitions the Commissioner for an extension of time extending to June 19, 1999, the period for response to the Office Action dated April 19, 1999. A check for \$110.00 and the responsive paper is attached.

If it should be determined that a longer extension is required to prevent this application from becoming abandoned, or for any other reason an insufficient fee has been paid, please charge any insufficiency to Deposit Account No. 50-0288.

Respectfully submitted,

Date: June 18, 1999

By: \_\_\_\_\_

Stephen Bongini  
Registration No. 40,917

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**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: ASSISTANT COMMISSIONER FOR PATENTS, WASHINGTON, D. C. 20231

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